Special Issue

Recent Applications of Precise Measurement and Metrology with Atomic, Optical and Molecular Systems

Message from the Guest Editor

This Special Issue will highlight the most recent advances in AMO measurements and their fundamental, metrological and practical applications. It will collect theoretical and experimental works dedicated to the study of problems emerging in the different contexts of AMO physics and metrology, including atomic and molecular clocks, matter-wave interferometry, optical magnetometry, gravimetry and inertial sensing, optical metrology, cavity ringdown molecular spectroscopy, and advanced techniques exploiting quantum measurements. This Special Issue invites researchers to submit original research and review articles related to the application and realization of precise AMO measures.

Guest Editor

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Deadline for manuscript submissions

closed (10 September 2024)



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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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